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| Department of Commerce, Patent and Trademark Office | Serial No.: 10/035,829 |
| | Filing Date: 10/18/2001 |
| SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT | Inventors: Vlad J. Novotny and Parvinder Dhillon |
| "Multi-Axis Micro-Electro-Mechanical Actuator" | Group Art Unit: 2874 |
| | Examiner Name: Stahl, Michael J. |
| | Attorney Docket No.: AO-666 |

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| *Examiner Initial | | Document Number | Date | Name | Class | Subclass | Filing Date, If Appropriate |
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Examiner M. Stahl

Date Considered 7/10/04

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with your communication to applicant.



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| | Filing Date: 10/18/2001 |
| SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT | First Named Inventor: Vlad J. Novotny |
| "Micro-Electro-Mechanical Switching System" | Group Art Unit: 2874 |
| | Examiner Name: Stahl, Michael J. |
| | Attorney Docket No.: AO-666 AONIP001C1 |

U.S. Patent / Patent Publication Documents

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